

**Notice of References Cited**Application/Control No.  
10/084,367Applicant(s)/Patent Under  
Reexamination  
NANJO ET AL.Examiner  
Toniae M. ThomasArt Unit  
2822

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**U.S. PATENT DOCUMENTS**

| * |   | Document Number<br>Country Code-Number-Kind Code | Date<br>MM-YYYY | Name | Classification |
|---|---|--|-----------------|------|----------------|
|   | A | US-  |                 |      |                |
|   | B | US-  |                 |      |                |
|   | C | US-  |                 |      |                |
|   | D | US-  |                 |      |                |
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